Sheet 1 of 3 Form PTO-1449 Docket Number (Optional) **Application Number** 4208.8US (99-0316.08/US) To be assign d INFORMATION DISCLOSURE CITATION Applicant Vern n M. Williams IN AN APPLICATION (Use several sheets if necessary) Group Art Unit Filing Date July 15, 2003 To be assigned 2518 **U.S. PATENT DOCUMENTS** EXAMINER DOCUMENT FILING DATE IF APPROPRIATE DATE CLASS SUBCLASS INITIAL NUMBER PD 4,138,672 02/1979 Kepchar 4,511,595 04/1985 Inoue 4,526,807 07/1985 Auerbach 4,578,155 03/1986 Halliwell et al. 4,695,258 09/1987 Hanson et al. 4,891,635 01/1990 Hata 4,954,873 09/1990 Lee et al. 5,007,576 04/1991 Congleton et al. 5,079,974 01/1992 Weiss et al. 5,141,680 08/1992 Almquist et al. 5,173,220 12/1992 Reiff et al. 5,174,943 12/1992 Hull 5,264,061 11/1993 Juskey et al. 5,278,442 01/1994 Prinz et al. PD 5,344,298 09/1994 Hull FOREIGN PATENT DOCUMENTS Translation DOCUMENT NUMBER DATE COUNTRY CLASS SUBCLASS NO PP 63-160351 07/1988 Japan PD 0 493 307 A2 07/1992 Europe PD 2001-217614 08/2001 Japan OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.) PD MILLER, Doyle, "New Laser-Directed Deposition Technology," HDI, p. 16 (August 2001). MILLER, Doyle, et al., "Maskless Mesoscale Materials Deposition," HDI, pp. 20-22 (September 2001). PD **EXAMINER** DATE CONSIDERED 12/30/2003 PHUC PANG Τ. EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.

Form PTO-1449				Docket Number (Optional) 4208.8US (99-0316.08/US)		Application Number To b assigned			
INFORMATION DISCLOSURE CITATION IN AN APPLICATION (Use several sheets if necessary)				Applicant Vernon M. Williams					
				Filing Date July 15, 2003		Group Art Unit To be assigned 2818			
		U.S.	PATENT I	DOCUMENTS					
EXAMINER INITIAL	DOCUMENT NUMBER	DATE		NAME	CLASS	SUBCLASS		G DATE ROPRIATE	
PP	5,461,769	10/1995		McGregor	~	_			
	5,484,314	01/1996		Farnworth					
	5,501,824	03/1996		Almquist et al.					
	5,510,066	04/1996		Fink et al.		-			
	5,541,367	07/1996		Swamy		_			
	5,545,367	08/1996		Bae et al.		-			
	5,569,349	10/1996		Almquist et al.					
	5,672,312	09/1997		Almquist et al.	•	_			
	5,676,904	10/1997		Almquist et al.		_			
	5,695,707	12/199	97	Almquist et al.	-				
	5,705,117	01/199		O'Connor et al.					
/	5,776,409	07/199		Almquist et al.		_			
	5,807,767	09/1998		Stroupe		_			
PD	5,855,063	01/1999		Schreiber et al.					
FOREIGN PATENT DOCUMENTS									
	DOCUMENT				Translation				
	NUMBER	DATE		COUNTRY	CLASS	SUBCLASS	YES	NO	
		07	THER DOC	LIMENTS	#- alvellag				
(Including Author, Title, Date, Pertinent Pages, Etc.)									
PHUE T. DANG			DATE CONSIDERED 12/30/2003						
EXAMINER: Initi	tial if citation consider	ered, whether or r	not citation is i	in conformance with Mi	PEP § 609;	Draw line the	ough cita	ation if	

Sheet 3 of 3 Form PTO-1449 Docket Number (Optional) **Application Number** To be assigned 4208.8US (99-0316.08/US) INFORMATION DISCLOSURE CITATION Applicant Vernon M. Williams IN AN APPLICATION (Use several sheets if necessary) Filing Date July 15, 2003 Group Art Unit To be assigned 2818 **U.S. PATENT DOCUMENTS EXAMINER** DOCUMENT FILING DATE IF APPROPRIATE DATE NAME CLASS SUBCLASS INITIAL NUMBER PD 5,855,836 01/1999 Leyden et al. 5,925,931 07/1999 Yamamoto 5,969,424 10/1999 Matsuki et al. 6,063,641 05/2000 Seki 6,081,430 06/2000 La Rue 6,096,574 08/2000 Smith 6,159,767 12/2000 Eichelberger 6,251,488 06/2001 Miller et al. 6,296,493 10/2001 Michiya 6,312,263 11/2001 Higuchi et al. 6,391,251 05/2002 Keicher et al. PD 6,468,891 10/2002 Williams FOREIGN PATENT DOCUMENTS DOCUMENT Translation DATE COUNTRY CLASS SUBCLASS NUMBER YES NO OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.) **EXAMINER** DATE CONSIDERED PHUC T. DANG 12/30/2003 EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.